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APPLICATION NO. FILING DATE		ILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/706,266		11/13/2003	Takaaki Shiota	061063-0306825	5650	
909	7590	03/25/2005		EXAMINER		
PILLSBURY WINTHROP, LLP P.O. BOX 10500				KUNEMUND, ROBERT M		
MCLEAN.)2	ART UNIT	PAPER NUMBER		

1722 DATE MAILED: 03/25/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

		A		A 1' 1/-'					
			Application No. Applicant(s)						
	Office Action Summers	10/706,26	5	SHIOTA ET AL.					
	Office Action Summary	Examiner	-	Art Unit					
		Robert M K		1765					
The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply									
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely. - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication. - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).									
Status									
1)	Responsive to communication(s) filed on								
2a) <u></u> □	This action is FINAL . 2b)⊠ This action is non-final.								
3)	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is								
	closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.								
Disposition of Claims									
4)🛛	4)⊠ Claim(s) <u>1-24</u> is/are pending in the application.								
•	4a) Of the above claim(s) is/are withdrawn from consideration.								
5) 🗌	5) Claim(s) is/are allowed.								
6)⊠	☑ Claim(s) <u>1-24</u> is/are rejected.								
	Claim(s) is/are objected to.								
8) Claim(s) are subject to restriction and/or election requirement.									
Application	on Papers								
9) The specification is objected to by the Examiner.									
10) ☐ The drawing(s) filed on is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.									
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).									
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).									
11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.									
Priority under 35 U.S.C. § 119									
12)⊠ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).									
	a) ⊠ All b) □ Some * c) □ None of:								
	1. Certified copies of the priority documents have been received.								
	2. Certified copies of the priority documents have been received in Application No								
	3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).								
* See the attached detailed Office action for a list of the certified copies not received.									
and the second s									
Attachment	(s)								
1) 🛛 Notice	of References Cited (PTO-892)		4) Interview Summary (PTO-413)					
2) 🔲 Notice 3) 🔯 Inform	of Draftsperson's Patent Drawing Review (PTO-Station Disclosure Statement(s) (PTO-1449 or PTO No(s)/Mail Date)/SB/08)	Paper No(s)/Mail Dal 5) Notice of Informal Pa 6) Other:	te)-152)				
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Art Unit: 1765

DETAILED ACTION

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

Claims 1 to 6, and 9 to 20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Falster (6,849,901).

The Falster reference teaches a method of creating a silicon wafer with an epitiaxial defect free layer on it, note, entire reference. A silicon wafer is creating by the seed pulling method where the V/G ratio is controlled and keeps at a level to create the desired silicon crystal. The V/G is taught to be a result effective variable, note col. 27. The wafer is sliced from the grown crystal. The wafer is then subjected to a heat treatment at temperatures above 1,100°c in an inert atmosphere. The annealing or

Art Unit: 1765

treatment conditions also affect the crystal, note cols, 18 and 19. The sole difference between the instant claims and the prior art is the defects in the wafer. However, in the absence of unexpected results, it would have been obvious to one of ordinary skill in the art to determine through routine experimentation the optimum, operable properties of the wafer, defects in the Falster process in order to create the desired wafer as the reference clearly shows changing conditions effect the defects in the wafers.

Claims 7, 8 and 21 to 24 are rejected under 35 U.S.C. 103(a) as being unpatentable over Falster (6,849,901).

The Falster reference is relied on for the same reasons as stated, supra, and differs in the removal of the silicon dioxide. However, in the absence of unexpected results, it would have been obvious to one of ordinary skill in the art to determine through routine experimentation the optimum, operable removal time of the silicon dioxide in the Falster process in order to treat the wafer without having oxygen present.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Robert M Kunemund whose telephone number is 571-272-1464. The examiner can normally be reached on 8 hours.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on 571-272-1465. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Application/Control Number: 10/706,266 Page 4

Art Unit: 1765

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

RMK

ROBERT KUNEMÚND PRIMARY PATENT EXAMINER A.U. 19721-